

Form PTO-1449  
(REV. 8-83)U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO.

2001 P 11914 US

SERIAL NO.

Not Yet Assigned

**INFORMATION DISCLOSURE CITATION**

(Use several sheets if necessary)

**DIRECT AND NON-DESTRUCTIVE MEASUREMENT  
OF RECESS DEPTH IN A WAFER**

APPLICANT

Chen et al.

EXAMINER

Not Yet Assigned

FILING DATE

September 28, 2001

GROUP

Not Yet Assigned

jc979 U.S. PTO  
09/965093**U. S. PATENT DOCUMENTS**

Examiner INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE
RR		4,840,487	Jun. 20, 1989	Noguchi et al.	356	355	
RR		5,691,540	Nov. 25, 1997	Halle et al.	250	372	
RR		6,124,141	Sep. 26, 2000	Muller et al.	257	529	
RR		6,275,297	Aug. 14, 2001	Zalicki	356	496	

**FOREIGN PATENT DOCUMENTS**

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION	
							YES	NO

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

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EXAMINER

RAEVIS

DATE CONSIDERED

4-24-02

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.